

Notice of References Cited	Application/Control No. 10/625,772		Applicant(s)/Patent Under Reexamination UCHIYAMA ET AL.	
	Examiner Daniel I. Walsh		Art Unit 2876	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,257,486	07-2001	Teicher et al.	235/380
*	B	US-2005/0110640	05-2005	Chung, Kevin Kwong-Tai	340/572.1
*	C	US-2004/0036623	02-2004	Chung, Kevin Kwong-Tai	340/825.49
*	D	US-2003/0052788	03-2003	Kwong-Tai Chung, Kevin	340/573.1
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP 2000-090215	03-2000	Japan	Inudou et al.	
	O	JP 2000-046939	02-2000	Japan	Yamamoto et al.	
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Position Monitoring with Hall Effect Sensors (http://www.sensorsmag.com/articles/0902/52/main.shtml) September 2002.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.